

Electronic Patent Application Fee Transmittal

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| Application Number: | 10792038 |
| Filing Date: | 03-Mar-2004 |
| Title of Invention: | Composition and process for post-etch removal of photoresist and/or sacrificial anti-reflective material deposited on a substrate |
| First Named Inventor/Applicant Name: | Melissa K. Rath |
| Filer: | Tristan Anne Fuierer |
| Attorney Docket Number: | ATMI-668 |

Filed as Large Entity

Utility under 35 USC 111(a) Filing Fees

| Description | Fee Code | Quantity | Amount | Sub-Total in USD(\$) |
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Basic Filing:

Pages:

Claims:

Miscellaneous-Filing:

Petition:

Patent-Appeals-and-Interference:

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| Notice of appeal | 1401 | 1 | 540 | 540 |
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Post-Allowance-and-Post-Issuance:

Extension-of-Time:

| Description | Fee Code | Quantity | Amount | Sub-Total in USD(\$) |
|-----------------------------------|----------|----------|--------|----------------------|
| Extension - 1 month with \$0 paid | 1251 | 1 | 130 | 130 |
| Miscellaneous: | | | | |
| Total in USD (\$) | | | | 670 |